

Bringing the lab to the fab: Robot-based inline measurement system for precise 3D surface inspection in vibrational environments

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Abstract—This paper presents the integrated design of a robot-based inline measurement system for precise 3D surface inspection on free-formed objects. The measurement system comprises a MAGLEV measurement platform that is mounted to an industrial robot and enables the out-of-plane tracking of an arbitrarily oriented sample surface. This establishes lab-like conditions for the integrated optical 3D measurement tool directly in a vibrational environment. Using a PID control architecture with a tracking control bandwidth of 600 Hz, the effects of a vibration signal with 15.5 $\mu\text{m rms}$ can be reduced to disturbances with 236 nm rms. The orientation-independent measurement performance is demonstrated by imaging a calibration standard with 20 μm pitch in various robot poses. Experiments show that the system is capable of reducing the axial measurement uncertainty by a factor of 12, enabling robot-based 3D measurements with sub-micrometer resolution on freeform surfaces in a vibrational environment.

Index Terms—Mechatronics, System integration, Vibration control.

I. INTRODUCTION

INDUSTRIAL high-tech manufacturing systems are facing a continuously growing demand for precision and throughput [1]. Inline measurements are consequently considered as a key factor for future industrial production [2], as they enable a 100% quality control [3]. This would allow for realtime optimization of the manufacturing process and production parameter settings [4], [5], enhancing the overall throughput as well as the production yield.

Surface properties, such as topography and roughness, are frequently considered as quality indicators, which is why precise 3D measurements are of growing interest in application fields ranging from the semiconductor to the automotive and consumer electronics sector [6]–[9]. The flexibility to quickly

align a 3D measurement tool (MT) to arbitrary locations on a freeform-shaped sample surface [10] and to extend its measurement range [11] can be provided by employing industrial robots. Current robot-based 3D imaging systems incorporate e.g. optical line sensors on a linear rail [12], [13] or stereo vision systems, both achieving resolutions down to 50 μm . However, the limited positioning accuracy of modern industrial robots, which is in the range of several tens of micrometers [14], makes robots themselves unsuitable for 3D surface measurements with single- or even sub-micrometer resolution [15].

Similar to the positioning uncertainty of robots, environmental vibrations in an industrial production line may cause relative motion between the MT and the sample surface, corrupting 3D measurements on the micrometer scale due to motion blur [16]. Considering these aspects, an inspection of each produced good with structural sizes in the single-micrometer range is usually not possible without impairing throughput, which is why typically sample-based inspections are conducted in a vibration-free lab environment.

In order to establish the required lab-like conditions for a conceptual precision 3D MT directly in the vibration-prone environment of an industrial production line, an active sample-tracking module aimed to act as a robot end-effector has been reported [17]. Since precision 3D MTs are typically rather bulky, a compact and lightweight scanning confocal chromatic sensor scanning confocal chromatic sensor (SCCS), targeted for robotic 3D measurement applications on a tracking module (TM) as an end-effector, has been proposed [18]. With concepts for the sub-components available, the integrated design of a precise robotic inline 3D measurement system with orientation-independent functionality is, however, still pending.

The contribution of this paper is i) the integrated system design of a robot-based inline measurement system for precise 3D surface inspection, and ii) the experimental validation of the orientation-independent 3D imaging performance in a vibrational environment. Focusing on the overall concept, a tailored TM with a sophisticated mechanical design is required for integration of the SCCS to proof the feasibility of robotic 3D measurements with sub-micrometer resolution.

II. INTEGRATED MEASUREMENT SYSTEM DESIGN

The targeted system concept of precise robotic inline 3D measurements on freeforms is illustrated in Fig. 1. By main-

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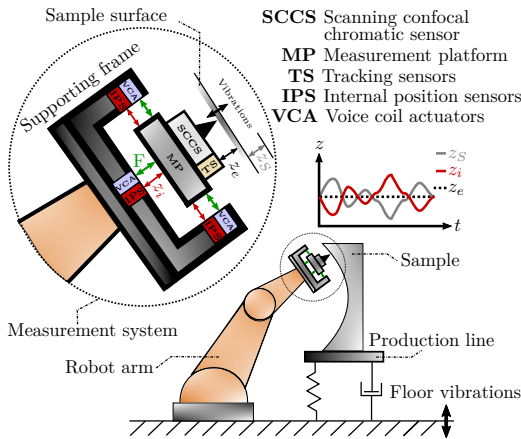


Fig. 1: Integrated robot-based measurement system for precise 3D surface inspection of freeform objects in vibrational environments. By means of feedback control, the position of the MT on the MP relative to the freeform surface is maintained constant.

taining a constant relative position of the measurement platform (MP) with respect to the sample surface, a contactless stiff link between the SCCS as a 3D MT and the surface area to be inspected is generated. In this way, the required lab-like conditions are established directly in a vibration-prone production line.

Figure 2 presents the novel integrated measurement system design, which comprises two main components, the TM to actively compensate disturbing vibrations and the SCCS to perform precision 3D measurements. The embedded electromagnetically levitated and actuated MP is tailored for the integration of the SCCS [18]. An actuation system (AS) based on voice coil actuators (VCAs) is used to achieve quasi-zero-stiffness actuation and thus, decoupling the MP from any external disturbances, such as vibrations from the robot. Eight identical VCAs A_1 - A_8 are integrated to apply bi-directional forces, yielding a balanced MP design for the six degree of freedom (DoF) motion control. Waiving for a passive gravity compensation mechanism enables orientation-independent system operability [19], as required for the targeted robotic measurements on free-form surfaces. Since a lightweight moving mass is desired, the coils of the VCAs are mounted on the MP, which is actuated within the air gaps between coils and magnet assemblies. The achievable actuation range of the MP is strongly dependent on these air gaps, as well as the placement of the VCAs. Therefore, a design trade-off between achievable actuation range and levers of torque is required, with the chosen design parameters discussed in Section IV. As depicted in Fig. 2, the out-of-plane DoFs z , ϕ_x and ϕ_y are actuated by A_1 - A_4 , while A_5 - A_8 enable in-plane positioning (x , y and ϕ_z) of the mover. In order to achieve a balanced system design and to minimize unintended crosstalk between the individual DoFs, the actuators are symmetrically placed beneath and around the center of mass of the moving part, i.e.

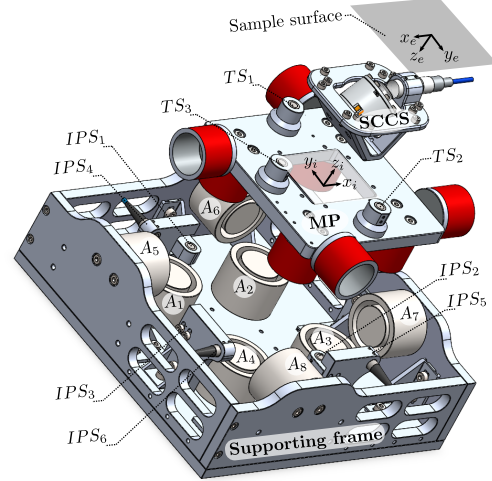


Fig. 2: Exploded view of the tracking module CAD model. VCAs are used for actuation of the MP in six DoFs. The SCCS is embedded in the MP. IPSs determine the position of the MP with respect to the supporting frame, while three TSs measure the external out-of-plane position and orientation relative to a sample surface.

MP with integrated SCCS.

Six internal position sensors (IPSs) are integrated to measure the MP position in all DoFs with respect to the supporting frame. The distance sensors IPS_4 - IPS_6 are placed around the MP to measure its in-plane position (x_i , y_i and $\phi_{z,i}$), while IPS_1 - IPS_3 are mounted beneath the MP to measure the out-of-plane position (z_i , $\phi_{x,i}$ and $\phi_{y,i}$).

In addition, the TM in Fig. 2 comprises three tracking sensors (TSs) TS_1 - TS_3 mounted on the MP to measure the external out-of-plane position of the MP relative to a sample surface (z_e , $\phi_{x,e}$ and $\phi_{y,e}$). Considering the concept presented in Fig. 1, the system design of the TM is capable of actively compensating disturbing vibrations in the three out-of-plane DoFs, while generating quasi-lab conditions for the precision 3D measurements with the SCCS.

III. SYSTEM MODELING

The decoupling between in- and out-of-plane actuation is achieved by the actuator placement discussed in Section II and shown in Fig. 2. Low crosstalk between the individual DoFs is ensured by a balanced system design and therefore neglected in the modeling phase, but analyzed in Section V-A. In order to ensure a constant current-to-force relation (quasi-zero-stiffness actuation), the hysteresis-free VCAs are operated around the MP's mid-position [20]. The ability of VCAs to apply bi-directional forces enables the required gravity compensation of the moving mass by orientation-dependent offset currents.

The TM dynamics for the MP's internal position ζ_i relative to the supporting frame and the external position ζ_e relative

to a sample surface are

$$\begin{bmatrix} \ddot{\zeta}_{i,oop} \\ \ddot{\zeta}_{i,ip} \end{bmatrix} = \mathbf{A} \mathbf{i} = \begin{bmatrix} \mathbf{A}_{oop} & \mathbf{0}_{3,3} \\ \mathbf{0}_{3,3} & \mathbf{A}_{ip} \end{bmatrix} \begin{bmatrix} \mathbf{i}_{oop} \\ \mathbf{i}_{ip} \end{bmatrix} \quad (1a)$$

$$\begin{bmatrix} \dot{\zeta}_{i,oop} \\ \dot{\zeta}_{i,ip} \end{bmatrix} = \begin{bmatrix} \mathbf{h}_{i,oop}(\mathbf{d}_{IPS,oop}) \\ \mathbf{h}_{i,ip}(\mathbf{d}_{IPS,ip}) \end{bmatrix} \quad (1b)$$

$$\zeta_{e,oop} = \mathbf{h}_{e,oop}(\mathbf{d}_{TS,oop}), \quad (1c)$$

with $\zeta_{i,oop} = [z_i \ \phi_{x,i} \ \phi_{y,i}]^T$ and $\zeta_{i,ip} = [x_i \ y_i \ \phi_{z,i}]^T$ the out-of- and in-plane MP position, \mathbf{A}_{oop} and \mathbf{A}_{ip} the according dynamic sub-matrices, and $\mathbf{i}_{oop} = [i_z \ i_{\phi_x} \ i_{\phi_y}]^T$ and $\mathbf{i}_{ip} = [i_x \ i_y \ i_{\phi_z}]^T$ being the in- and out-of-plane current vectors [17]. Trigonometric functions, $\mathbf{h}_{i,oop}$ and $\mathbf{h}_{i,ip}$, are applied to transform the measured out-of-plane and in-plane distances $\mathbf{d}_{IPS,oop} = [d_{IPS,1}, d_{IPS,2}, d_{IPS,3}]$ and $\mathbf{d}_{IPS,ip} = [d_{IPS,4}, d_{IPS,5}, d_{IPS,6}]$ into the actual MP's position ζ_i with respect to the supporting frame (internal position). A similar transformation $\mathbf{h}_{e,oop}$ is applied to the distances $\mathbf{d}_{TS,oop} = [d_{TS,1}, d_{TS,2}, d_{TS,3}]$, measured by the three TSs, in order to calculate the MP's position ζ_e relative to a sample surface (external position). Considering the two coordinate systems in Fig. 2, the dynamics of ζ_i and ζ_e are the same except for the sign, yielding

$$\dot{\zeta}_{e,oop} = \dot{\mathbf{h}}_{e,oop}(\mathbf{d}_{TS,oop}) = -\dot{\zeta}_{i,oop}. \quad (2)$$

Assuming quasi-zero-stiffness actuation, the dynamic matrix from Eq. 1a

$$\mathbf{A} = \begin{bmatrix} \frac{4k_m}{m} & 0 & 0 & 0 & 0 & 0 \\ 0 & \frac{4k_m l_x}{I_x} & 0 & 0 & 0 & 0 \\ 0 & 0 & \frac{4k_m l_y}{I_y} & 0 & 0 & 0 \\ 0 & 0 & 0 & \frac{2k_m}{m} & 0 & 0 \\ 0 & 0 & 0 & 0 & \frac{2k_m}{m} & 0 \\ 0 & 0 & 0 & 0 & 0 & \frac{4k_m l_z}{I_z} \end{bmatrix} \quad (3)$$

has only entries on the main diagonal, with m the total moving mass, k_m the VCA motor constant, l_x , l_y and l_z the levers of torque and I_x , I_y and I_z indicating the according moments of inertia in the rotational DoFs.

A linear transformation $\mathbf{i}_a = \mathbf{T} \mathbf{i}$ with the transformation matrix

$$\mathbf{T} = \begin{bmatrix} \mathbf{T}_{oop} & \mathbf{0}_{4,3} \\ \mathbf{0}_{4,3} & \mathbf{T}_{ip} \end{bmatrix} = \begin{bmatrix} 1 & 1 & 1 & 0 & 0 & 0 \\ 1 & 1 & -1 & 0 & 0 & 0 \\ 1 & -1 & -1 & 0 & 0 & 0 \\ 1 & -1 & 1 & 0 & 0 & 0 \\ 0 & 0 & 0 & 1 & 0 & -1 \\ 0 & 0 & 0 & 0 & -1 & -1 \\ 0 & 0 & 0 & -1 & 0 & -1 \\ 0 & 0 & 0 & 0 & 1 & -1 \end{bmatrix} \quad (4)$$

is applied to map the six currents from the vector \mathbf{i} onto the individual currents $\mathbf{i}_a = [i_1 \ i_2 \ i_3 \ i_4 \ i_5 \ i_6 \ i_7 \ i_8]^T$ applicable to the eight VCA coils.

IV. SYSTEM IMPLEMENTATION

Based on the integrated measurement system design from Section II, the individual system components are implemented with the design trade-offs discussed in detail in the following.

TABLE I: Design parameters of the implemented TM.

Parameter	Value	Description
k_m	12.7 N A ⁻¹	VCA motor constant
m	890 g	Levitated and moving mass
l	50 mm	Lever of torque ϕ_x, ϕ_y, ϕ_z
I_x	1.47 mm kg	Moment of inertia ϕ_x
I_y	1.482 mm kg	Moment of inertia ϕ_y
I_z	2.74 mm kg	Moment of inertia ϕ_z

A. Mechanical components

All mechanical parts of the TM are manufactured out of aluminum to achieve the targeted stiff system and shift first structural modes to high frequencies. According to conducted FEM simulations, the first structural mode of the MP is excited at about 1.9 kHz (data not shown). The assembled system measures $220 \times 220 \times 72 \text{ mm}^3$ in size and the total weight is about 5.25 kg. The supporting frame provides mounting holes for the magnet housings of the VCAs as well as brackets for the six IPSs. In the 10 mm thick and square MP with a side length of 125 mm a mounting hole for the SCCS is included. In addition, the coils of the VCAs can be mounted to the MP and brackets for the three TSs are provided. The total mass m of the assembled MP which needs to be levitated and actuated is about 890 g.

B. Actuation system

Eight conventional VCAs (VCAR0087-0062-00A, Supt-Motion, Suzhou, China) are selected to apply bi-directional forces to the MP and to enable the target orientation-independent operability of the TM. Each VCA shows an air gap of 500 μm and can provide 20 N continuous force. Considering the aforementioned design trade-off between applicable torque and achievable rotational actuation range, all levers of torque $l_x = l_y = l_z = l$ are chosen to 50 mm. With the MP in its center position, the implemented TM achieves an actuation range of about $\pm 175 \mu\text{m}$ and $\pm 3 \text{ mrad}$ in the translational and rotational DoFs. The design parameters from the dynamic matrix in Eq. 3 are summarized in Tab. I. Based on the high-power operational amplifier OPA541 (Texas Instruments, Dallas, Texas, United States), custom-made analog proportional-integral (PI) voltage-controlled current controllers are implemented to apply the desired currents to the VCAs of the MP and the fast steering mirror (FSM) of the SCCS. The bandwidth of each analog current control loop (see $\mathbf{i}_a(\mathbf{u}_{a,r})$ and $\mathbf{i}_b(\mathbf{u}_{b,r})$ in Fig. 3b) is set to 15 kHz to avoid phase lag in the position control loops.

C. Internal position and tracking sensors

Capacitive displacement sensors (CSH05, Micro-Epsilon, Ortenburg, Germany) are used to measure the six distances \mathbf{d}_{IPS} between supporting frame and MP and the three distances \mathbf{d}_{TS} between MP and sample surface. Each of the nine sensor channels shows a measurement range of 500 μm with a constant gain of 50 $\mu\text{m V}^{-1}$. After applying the nonlinear transformations in Eq. 1b and 1c to calculate the internal and external position of the MP, a position noise of 17 nm rms and 400 nrad rms for each translational and rotational DoF is achieved, respectively.

D. Scanning confocal chromatic sensor for 3D imaging

The integrated design of the SCCS [18] includes a high performance 2D FSM [21] to manipulate the optical path of a high precision 1D confocal chromatic sensor (CCS) (IFS2404-2, Micro-Epsilon, Ortenburg, Germany). A multi-input-multi-output (MIMO) H_∞ controller C_{FSM} for the FSM axes is implemented to enable quick and precise scanning of the CCS's measurement spot across the surface area of interest. A data-driven image reconstruction procedure is implemented combining the FSM deflection angles and the correspondingly measured distances to the sample surface, in order to obtain an accurate 3D surface image. The SCCS can measure a volume of $0.35 \times 0.25 \times 1.8 \text{ mm}^3$ with frame rates of up to 1 fps. Moreover, high resolution scans of arbitrary regions of interests (RoIs) can be performed with a lateral and axial resolution is of $2.5 \mu\text{m}$ and 76 nm , respectively. Using the holes provided by the SCCS's aluminum alignment frame, the 3D MT is mounted to the MP (see Fig. 2) such that the measuring mid-range of the SCCS coincides with the mid-range of the capacitive TSs, which is about $250 \mu\text{m}$ in z -direction. A more detailed description of the compact SCCS enabling precision 3D measurements can be found in [18].

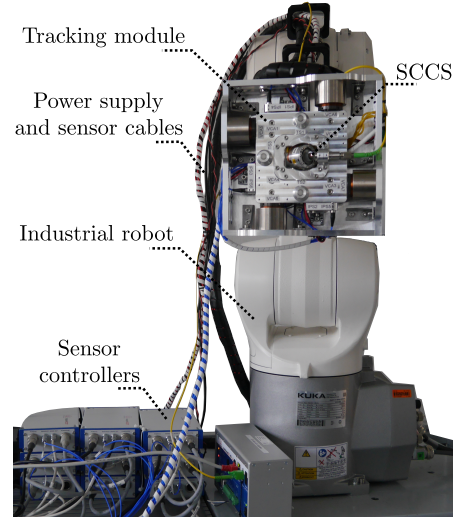
E. Rapid prototyping systems

High sampling rates are desired for the system in- and outputs to avoid phase lag and enable a high performance control of the MP position as well as performing precise scans with the FSM. Therefore, both digital position controllers in Fig. 3b, C_{MP} and C_{FSM} , are implemented on a dSPACE MicroLabBox (MicroLabBox, dSPACE GmbH, Paderborn, Germany). To acquire the CCS's sensing signal and the actual angular deflection of the FSM, an industrial DAQ system (EK1100 and EL3702, Beckhoff Automation GmbH & Co. KG, Verl, Germany) is used. After acquisition of an entire measurement set, the synchronized data is applied to the image reconstruction procedure to obtain the desired 3D image. Both rapid prototyping systems operate at a sampling frequency of 40 kHz.

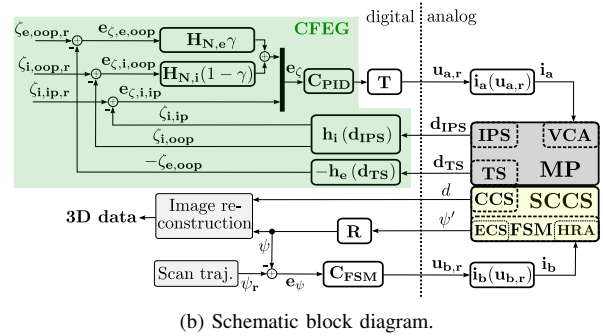
F. System architecture

Based on the system design presented in Fig. 2, the TM is implemented and mounted to an industrial robot arm (KR10-2 R900, KUKA, Augsburg, Germany), as depicted in Fig. 3a.

Figure 3b represents the architecture of the individual system components in a schematic block diagram. Based on a cross-fading error gain (CFEG) [22], the MP can either be positioned relative to the supporting frame in six DoFs when the robot is repositioning (stabilization mode) or actively track a sample surface in the out-of-plane DoFs (tracking mode). The actual MP positioning error e_ζ is applied to the position controller C_{PID} and the reference voltages $u_{a,r}$ for the voltage-controlled current amplifiers $i_a(u_{a,r})$ are calculated using the linear transformation matrix T from Eq. 4. The desired currents i_a are applied to the VCAs and the actual MP position is calculated by applying the distances measured by the IPS and TS system to Eq. 1b and 1c.



(a) Implemented TM mounted on an industrial robot arm.



(b) Schematic block diagram.

Fig. 3: System implementation. a) depicts the lab setup with the integrated TM mounted on a robot. The schematic block diagram in b) illustrates the architecture of the individual system components.

To precisely deflect the FSM axes of the SCCS according to the desired scan trajectory, a high-performance motion controller C_{FSM} sets the reference voltage $u_{b,r}$ for the voltage-controlled current amplifiers $i_b(u_{b,r})$. The output currents i_b are applied to the 2D hybrid-reluctance actuator (HRA) of the FSM. As the actuator and sensor axes of the FSM are rotated by 45° , the measured deflection ψ' by the integrated eddy current sensors (ECSs) is transformed using a rotation matrix R [18]. The actual FSM deflection ψ together with the distance d measured by the CCS, is applied to a calibration-based image reconstruction procedure which provides the targeted 3D data of the sample surface.

V. SYSTEM ANALYSIS AND CONTROL DESIGN

The TM comprises two individual sensor systems to measure i) the internal MP position relative the supporting frame

and ii) the external out-of-plane MP position relative to a sample surface. The internal and external TM dynamics measured with the IPSs and TSs, respectively, are analyzed in the following. Moreover, a control structure enabling the smooth transition between stabilization of the MP and the tracking of a sample surface, is presented.

A. Analysis of system dynamics

In a first step, the TM's internal dynamics are identified in closed-loop operation by means of low-bandwidth floating-mass model-based proportional-integral-derivative (PID) controller designed for each DoF to stabilize the MP in a free-floating position relative to the supporting frame. Sinusoidal sweeps with small amplitudes of 1 μm and 50 μrad are applied as reference for the low-bandwidth single-input single-output (SISO) controller of each translational and rotational DoF, respectively. By dividing the measured internal position signal by the according controller output, the individual internal system dynamics are obtained. Due to the balanced system design, the measured crosstalk between the individual DoFs for frequencies up to 1 kHz is 14 to 25 dB lower than the related system dynamics (data not shown). The dynamics analysis is exemplarily shown for DoF z in Fig. 4 and includes the time delay of the rapid prototyping system as well as the dynamics of the AS, the MP and IPS system. In the frequency range between 30 and 1.4 kHz, good agreement between the measured internal dynamics G_i and the floating mass model (FMM) G_{FMM} is achieved.

As given by Eq. 2, the internal and external out-of-plane MP dynamics show equal magnitude and a phase shift 180° (see [17]). By repeating the identification process in tracking control mode, the three external out-of-plane TM dynamics are identified. As expected and exemplarily shown in Fig. 4 for DoF z , the internal dynamics G_i match the 180° phase-shifted external dynamics G_e . Measured structural modes above 1.4 kHz are measured slightly different due to different mounting positions of IPS_1 - IPS_3 and TS_1 - TS_3 in the xy -plane (see Fig. 2).

B. Motion control

A SISO PID control approach for the two individual control tasks of the MP, i) the stabilization relative to the supporting frame and ii) the active tracking of a sample surface, is pursued as the measured crosstalk is sufficiently low [19]. For each internal and external DoF, tamed PID controllers

$$C_{PID} = k_p + \frac{k_i}{s} + \frac{k_d s}{1 + \frac{s}{\omega_t}} \quad (5)$$

are synthesized in a loop shaping approach aiming to maximize the positioning control bandwidth [23].

As previously discussed in Section V-A, the internal and external out-of-plane MP dynamics are similar, enabling the use of the same PID parameters for both control tasks, stabilization and tracking, by shifting the external position measured by 180° [22]. Excitation of the structural modes identified at frequencies beyond 1.4 kHz is suppressed by

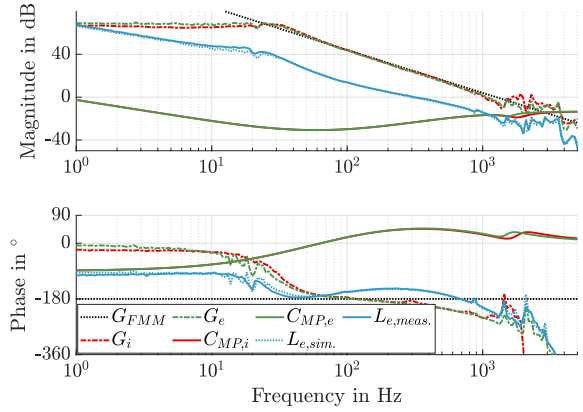


Fig. 4: Analysis of system dynamics and controller design of DoF z . The measured in- and external dynamics are in good accordance ($G_i \approx G_e$) and match the mathematical floating mass model G_{FMM} . The stabilization controller $C_{MP,i}$ and tracking controller $G_{MP,e}$ differ only by tailored notch filters at frequencies above 1.4 kHz.

TABLE II: Designed GMs and PMs of internal (stabilization) and external (tracking) position control loop gains.

	DoF	ω_c	GM	PM
stabilization	z_i	340 Hz	9.8 dB	30.5°
	$\phi_{x,i}$	320 Hz	8.7 dB	31.8°
	$\phi_{y,i}$	320 Hz	8.8 dB	31.7°
	x_i	300 Hz	8.1 dB	29.8°
	y_i	300 Hz	8.3 dB	30.3°
	$\phi_{z,i}$	290 Hz	8.1 dB	27.9°
tracking	z_e	340 Hz	9.7 dB	30.4°
	$\phi_{x,e}$	320 Hz	8.1 dB	29.9°
	$\phi_{y,e}$	320 Hz	8.4 dB	29.1°

applying tailored notch filters $H_{N,k}$, $k \in \{i, e\}$. The resulting combined structure of the MP motion controller

$$C_{MP,k} = C_{PID} H_{N,k}, \quad k \in \{i, e\} \quad (6)$$

is designed for each in- and external DoF with a crossover frequency of about 320 Hz. To ensure robustness, sufficient gain margin (GM) and phase margin (PM) of at least 8 dB and 25° for each DoF are targeted in the controller synthesis. A summary of the designed GMs and PMs at the desired crossover frequencies ω_c of the individual internal and external position control loops is listed in Tab. II.

In Fig. 4 the controllers designed for the two individual control tasks in DoF z are exemplarily shown. As can be seen, the controllers $C_{MP,i}$ and $C_{MP,e}$ differ only by the tailored and individually designed notch filters, applied at frequencies above 1.4 kHz to cancel the measured structural modes. Between the resulting simulated and measured loops gains of the external position, $L_{e,sim.}$ and $L_{e,meas.}$, good accordance is achieved. The crossover frequency of 340 Hz is clearly visible, together with the gain and phase margins of 9.8 dB and 30.5°.

Figure 5 shows the measured complementary sensitivities T and sensitivities S of the three out-of-plane DoFs in tracking

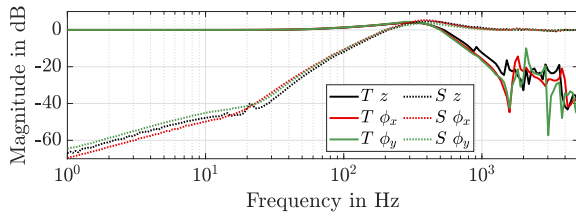


Fig. 5: Complementary sensitivity T and sensitivity S of the implemented 3 DoF tracking control. A -3 dB tracking control bandwidth of about 600 Hz and good disturbance rejection at low frequencies are obtained.

mode, while the MP is stabilized in-plane relative to the supporting frame. A -3 dB tracking control bandwidth of about 600 Hz is achieved in all three DoFs. According to the sensitivities (dotted lines), good disturbance rejection is obtained for lower frequencies, e.g. a vibration component with a frequency of 10 Hz can be attenuated by about 48 dB in DoF z , which equals a factor of about 250. An efficient transition between the stabilization and tracking mode is enabled by implementation of the CFEG-based control scheme from Fig. 3b [22].

VI. EXPERIMENTAL PERFORMANCE EVALUATION

A. Vibration compensation by active sample-tracking

In a first step, the vibration compensation of floor vibration spectra is demonstrated. Therefore, a randomized signal with $15.5 \mu\text{m rms}$ meeting the VC-A norm [24] is applied to a 1 DoF shaker, emulating standardized floor vibrations in DoF z . Using the industrial robot, the TM is aligned to the sample surface on the shaker. With the TM in stabilization mode, the relative motion between the SCCS and the sample surface is represented by the positioning error e of DoF z in grey in Fig. 6. Repeating the measurement for the same vibration signal with the TM in tracking mode, a residual error of only 236 nm rms is obtained (zoomed plot of Fig 6). Thus, the control-induced stiff link between the SCCS and the sample surface is capable of attenuating 98.5 % of the vibration-caused relative motion in DoF z .

B. Robot-based 3D imaging in vibrational environment

In order to evaluate the TM's 3D imaging performance in vibrational environments, a calibration standard with $20 \mu\text{m}$ pitch and step heights of $25 \mu\text{m}$ (Nanuler Calibration Standard, Applied NanoStructures Inc., Mountain view, CA, USA) is mounted to the 1-DoF shaker. 3D images of the sample surface are acquired by applying a Lissajous scan trajectory to the FSM with a total measurement time of $T = 10 \text{ s}$. A reference measurement of the grating structure is conducted with enabled tracking control mode, but without applying vibrations to the shaker. The resulting reference image of the sample surface is shown in Fig. 7a, with the grating pitch of $20 \mu\text{m}$ measured correctly. The measured height z along the top of the grating at $x = 140 \mu\text{m}$ in Fig. 7b is evaluated to 571 nm rms and serves as a reference value. As the CCS's

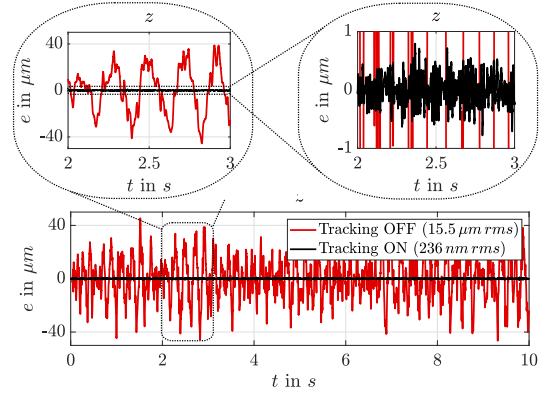


Fig. 6: Vibration compensation by active sample-tracking. With the TM in tracking mode (black), a $15.5 \mu\text{m rms}$ vibration signal (VC-A norm) is attenuated to a residual error of 236 nm rms .

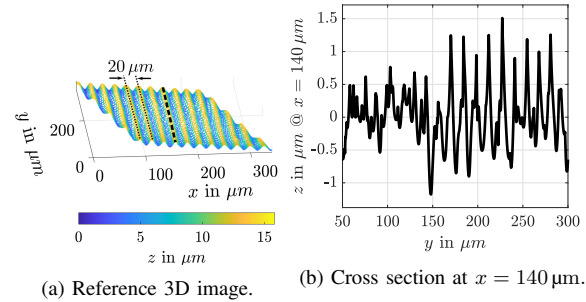


Fig. 7: Reference measurement of the grating structure. a) The grating pitch of $20 \mu\text{m}$ is clearly visible. b) shows the measured z -ripple along the grating top at $x = 140 \mu\text{m}$.

light spot diameters equals the structural width ($10 \mu\text{m}$), the periodical peaks in Fig. 7b are most probably caused by light scattering at the sharp grating edges.

The 3D imaging capability of the TM in vibrational environment and different static robot poses is shown in Fig. 8. Using the robot arm, the TM is aligned to the 1-DoF shaker, on which the calibration standard with the $20 \mu\text{m}$ grating is mounted, such that the three TSs and the SCCS are in range. To demonstrate the systems orientation-independent operability, the system performance in horizontal and vertical orientation is investigated (see Fig. 8a and 8b).

Again, a vibration signal according to the VC-A norm is applied to the 1-DoF shaker, introducing relative motion between the SCCS and the sample surface. With the TM in stabilization mode, motion blur in the 3D measurements (see Fig. 8c and 8d) is caused and the $20 \mu\text{m}$ grating structure is not visible. By enabling the tracking mode, the targeted contactless stiff link between SCCS and sample surface is established. The 3D measurements for the measurement system in tracking mode and the same vibration signal applied to the shaker are shown in Fig. 8e and 8f. The $20 \mu\text{m}$ grating pitch is

clearly visible and measured correctly in both orientations. To quantify the measurement system performance, the cross sections at $x = 140 \mu\text{m}$ in the 3D images, indicated in dashed black, is evaluated and shown in Fig. 8g and 8h for dis- and enabled tracking control, respectively. In both orientations, the measurement uncertainty is reduced from about $11 \mu\text{m rms}$ to 900 nm rms , improving the 3D imaging performance by a factor of 12. Compared to the reference 3D measurement in Fig. 7, the imaging resolution is in the same order of magnitude.

In summary, the integrated robotic measurement system successfully enables precision 3D measurements on freeform surfaces with a resolution on the sub-micrometer scale, compensating for 98.5% of disturbing vibrations in the translational out-of-plane DoF.

VII. CONCLUSION

This paper presents a measurement system for robotic precision 3D measurements on freeform surfaces in arbitrary orientations. The system design comprises a MAGLEV MP with three integrated TSs measuring the out-of-plane position of the SCCS as a 3D MT relative to a sample surface. In addition, six IPSs measure the MP position in six DoFs with respect to the supporting frame. Applying a SISO PID control architecture, the MP can track a sample surface while it is stabilized in-plane relative to the supporting frame. A positioning control bandwidth of about 600 Hz is achieved for each DoF. Standardized floor vibration profiles are applied to a sample surface in order to evaluate the system performance. Experimental results demonstrate that 98.5% of disturbing vibrations are actively compensated by the TM in the translational out-of-plane DoF. An industrial robot is used to position the TM in different orientations relative to a vibrating $20 \mu\text{m}$ grating structure. By enabling the tracking control, the measurement uncertainty is improved by a factor of 12, enabling robot-based precision 3D measurements on freeform surfaces on the sub-micrometer scale in vibrational environments.

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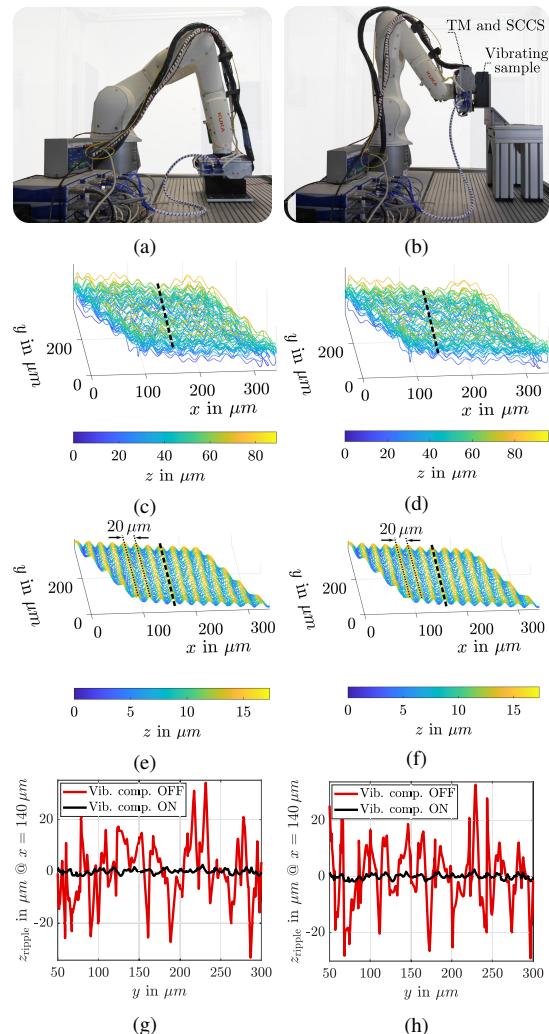


Fig. 8: Robot-based precision 3D imaging in vibrational environment. a) and b) show the measurement system positioned by the robot in horizontal and vertical direction. c) and d) illustrate blurry 3D images for disabled tracking control. e) and f) demonstrate the precise measurement of the grating structure with enabled out-of-plane tracking control. In g) and h), the measurement uncertainty along the cross section at $x = 140 \mu\text{m}$ in the 3D measurements (dashed black line) is shown for enabled and disabled tracking mode.

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